

EB 1 9 2002

V026159219

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/905,320  
Filing Date July 13, 2001  
Inventor Cem Basceri et al.  
Assignee Micron Technology, Inc.  
Group Art Unit 1762  
Examiner Eric Fuller  
Attorney's Docket No. MI22-1657  
Title: Chemical Vapor Deposition Methods of Forming Barium Strontium Titanate Comprising Dielectric Layers, Including Such Layers Having a Varied Concentration of Barium and Strontium Within the Layer

**RESPONSE TO DECEMBER 19, 2001 OFFICE ACTION**

To: Box Non-Fee Amendment  
Assistant Commissioner for Patents  
Washington, D.C. 20231

**VIA EXPRESS MAIL**

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Responsive to the Office Action dated December 19, 2001, Applicant amends and remarks as follows:

**AMENDMENTS**

**In the Specification**

Please replace the paragraph beginning at line 6 on page 19 with the following clean replacement paragraph in accordance with 37 CFR § 1.121(b)(1)(ii). A marked-up version showing amendments to the specification paragraph being changed is provided in one or more

MI221657.M01

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